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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/043,276	01/14/2002	Goro Nakatani	040894-5755	4701	
9629	7590 06/20/2	6	EXAM	EXAMINER	
	LEWIS & BOCKI	IM, JUNGHWA M			
1111 PENNSYLVANIA AVENUE NW WASHINGTON, DC 20004		. 14 4A	ART UNIT	PAPER NUMBER	
	ŕ		2811		
				DATE MAILED: 06/20/2006	

Please find below and/or attached an Office communication concerning this application or proceeding.

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		Application No.	Applicant(s)			
Office Action Summary		10/043,276	NAKATANI ET AL.			
		Examiner	Art Unit			
		Junghwa M. Im	2811			
Period f	The MAILING DATE of this communication apports or Reply	pears on the cover sheet w	th the correspondence address			
THE - External control	HORTENED STATUTORY PERIOD FOR REPL MAILING DATE OF THIS COMMUNICATION. ensions of time may be available under the provisions of 37 CFR 1.1 or SIX (6) MONTHS from the mailing date of this communication. e period for reply specified above is less than thirty (30) days, a repl O period for reply is specified above, the maximum statutory period ure to reply within the set or extended period for reply will, by statute reply received by the Office later than three months after the mailin ned patent term adjustment. See 37 CFR 1.704(b).	136(a). In no event, however, may a rely within the statutory minimum of thin will apply and will expire SIX (6) MON e, cause the application to become AB	eply be timely filed  y (30) days will be considered timely.  THS from the mailing date of this communication  ANDONED (35 U.S.C. § 133).	on.		
Status						
1)⊠	Responsive to communication(s) filed on 14 N	March 2006.				
· · ·		s action is non-final.				
3)	Since this application is in condition for allowa	ance except for formal matt	ers, prosecution as to the merits i	s		
	closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.					
Disposit	tion of Claims					
4)⊠	Claim(s) 1,3 and 8-13 is/are pending in the ap	plication.				
	4a) Of the above claim(s) is/are withdrawn from consideration.					
5)	Claim(s) is/are allowed.					
6)⊠	☐ Claim(s) <u>1,3 and 8-13</u> is/are rejected.					
7)	Claim(s) is/are objected to.					
8)[						
Applicat	tion Papers					
9)[	The specification is objected to by the Examine	er.				
10)	10) The drawing(s) filed on is/are: a) accepted or b) because to by the Examiner.					
	Applicant may not request that any objection to the	drawing(s) be held in abeyar	ice. See 37 CFR 1.85(a).			
	Replacement drawing sheet(s) including the correct	ction is required if the drawing	(s) is objected to. See 37 CFR 1.121(	(d).		
11)	The oath or declaration is objected to by the Ex	xaminer. Note the attached	I Office Action or form PTO-152.			
Priority	under 35 U.S.C. § 119					
a)	Acknowledgment is made of a claim for foreign   All   b)   Some * c)   None of:  1.   Certified copies of the priority document   2.   Certified copies of the priority document   3.   Copies of the certified copies of the priority application from the International Burea   See the attached detailed Office action for a list	ts have been received. ts have been received in A prity documents have been tu (PCT Rule 17.2(a)).	pplication No received in this National Stage			
Attachmer						
	ce of References Cited (PTO-892) ce of Draftsperson's Patent Drawing Review (PTO-948)		Summary (PTO-413) s)/Mail Date			
3) 🔲 Info	rmation Disclosure Statement(s) (PTO-1449 or PTO/SB/08) er No(s)/Mail Date	F	nformal Patent Application (PTO-152)			

#### **DETAILED ACTION**

### Continued Examination Under 37 CFR 1.114

A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on March 14, 2005 has been entered.

#### Claim Rejections - 35 USC § 112

The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

Claims 1 and 8 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

Claims 1 and 8 recite that polyimide directly surrounds gold metal interconnect and a portion of the resin layer is removed. This indicates that there are a planarized polyimide and the polyimide resin layer.

## Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are

such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1, 3, 8 and 10-13 are rejected under 35 U.S.C. 103(a) as being unpatentable over Loboda et al. (US 5818071), hereinafter Loboda in view of Braeckelmann et al. (US 6218302), hereinafter Braeckelmann.

Regarding claim 1, insofar as understood, Fig. 1 of Loboda shows semiconductor device comprising:

a first interconnect layer (3) arranged above a substrate on which a functional semiconductor region (2) is formed;

a silicon nitride film (5) a metal interconnect layer (7) said metal interconnect layer being consist of gold material (col. 1, line 59); and

a planarized polyimide (9) which is directly on the a silicon nitride film and surrounding the metal interconnect layer.

Fig. 1 of Loboda shows most aspect of the instant invention except an inter layer dielectric and the polyimide layer is removed at a part of a region of the metal interconnect layer and a bond wire is connected to the region of the metal interconnect layer. Fig. 11 of Braeckelmann shows that an inter layer dielectric (22) and a silicon nitride film (23) formed so as to cover entirely a top surface of said interlayer dielectric, covering over said silicon nitride film covering a surface of the first interconnect layer and the polyimide layer is removed at a part of a region of the metal interconnect layer and a bond wire (1104) is connected to the region of the metal interconnect layer.

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Art Unit: 2811

It would have been obvious to one of ordinary skill in the art at the time of the invention to incorporate the teachings of Loboda to the device of Braeckelmann in order to have an additional inter layer dielectric layer under the silicon nitride layer for structural strength and the polyimide layer removed at a part of a region of the metal interconnect layer for wire connection.

Regarding claim 3, Braeckelmann discloses that the silicon nitride film is deposited by plasma deposit (col. 3, lines 49-51).

In addition, "high-density plasma CVD" is a process designation, and would thus not carry patentable weight in this claim drawn to a product. See *In re Thorp*, 227 USPQ 964 (Fed. Cir. 1985).

Regarding claim 8, insofar as understood, Fig. 1 of Loboda shows a semiconductor device comprising:

a first interconnect layer (5) covering a first portion of a surface of a functional semiconductor region (2);

a silicon nitride film (5) around the contacting hole on the surface of the first interconnect layer;

a barrier layer (8) covering the contacting hole and a portion of a surface of the silicon nitride film around the contacting hole, thereby forming a barrier layer region (col. 3, lines 65-68);

a metal interconnect region (7) consist of gold material (col. 7, lines 23-26) covering over the barrier region, thereby forming a metal interconnect region; and

a planarized polyimide (9) covering the metal interconnect layer and the silicon nitride surface around the metal interconnect region.

Art Unit: 2811

Fig. 1 of Loboda shows most aspect of the instant invention except an inter layer dielectric and that a portion of the polyimide layer is removed. Fig. 11 of Braeckelmann shows an inter layer dielectric and silicon nitride covering a top surface of said inter layer dielectric an inter layer dielectric covering a second portion of the surface of the functional semiconductor region and a portion of a surface of said first interconnect layer, thereby forming a contacting hole on the surface of the first interconnect layer and the polyimide layer is removed at a part of a region of the metal interconnect layer and a bond wire (1104) is connected to the region of the metal interconnect layer.

It would have been obvious to one of ordinary skill in the art at the time of the invention to incorporate the teachings of Loboda to the device of Braeckelmann in order to have an additional inter layer dielectric layer under the silicon nitride layer for structural strength and the polyimide layer removed at a part of a region of the metal interconnect layer for wire connection.

Regarding claims 10 and 11, Braeckelmann discloses the first interconnect layer consists of aluminum (col. 3, lines 25-26).

Regarding claim 12, Braeckelmann discloses the inter layer dielectric consists of USG film (col. 3, lines 47-49).

Regarding claim 13, Fig. 11 of Braeckelmann shows the functional semiconductor region further comprises a polysilicon gate (108; col.2, lines 57-58) isolated from the first interconnect layer by a second dielectric layer (110), wherein the first interconnect layer is connected to the polysilicon gate through a contacting area (116) disposed within the second dielectric layer.

Claim 9 is rejected under 35 U.S.C. 103(a) as being unpatentable over Loboda and Braeckelmann as applied to claim 8 above, and further in view of Toyosawa et al. (US 6441467), hereinafter Toyosawa.

Regarding claim 9, the combied teachings of Loboda and Braeckelmann shows substantially the entire claimed structure except "the barrier layer consists of titanium." Toyosawa discloses that the barrier layer consists of titanium (col. 7, lines 48-50).

It would have been obvious to one of ordinary skill in the art at the time of the invention to incorporate the teaching of Toyosawa to the device of Braeckelmann in order to have the barrier layer consisted of titanium to diffusion of the metallic compound to the neighboring layer while using the well-known barrier material.

#### Response to Arguments

Applicant's arguments with respect to pending claims have been considered but are moot in view of the new ground(s) of rejection.

#### Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Junghwa M. Im whose telephone number is (571) 272-1655. The examiner can normally be reached on MON.-FRI. 8:30AM-5:00PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Eddie C. Lee can be reached on (571) 272-1732. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

jmi

EDDIE LEE SUPERVISORY PATENT EXAMINER

TECHNOLOGY CENTER 2800